

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): UCHIDA, et al.

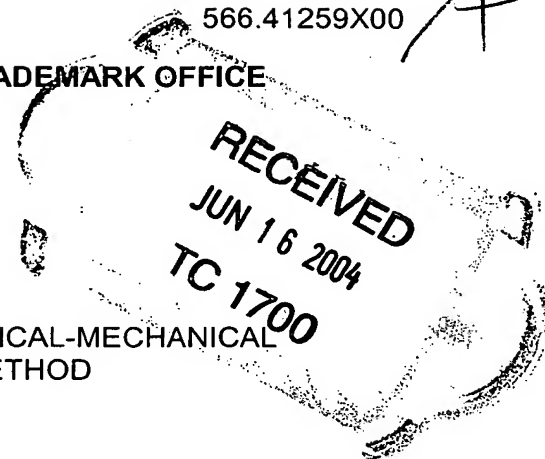
Application No.: 10/069,404

Filed: February 26, 2002

For: POLISHING MEDIUM FOR CHEMICAL-MECHANICAL  
POLISHING, AND POLISHING METHOD

Examiner: L. Umez Eronini

Group: 1765



AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

June 8, 2004

Sir:

In response to the Office Action mailed December 8, 2003, please amend the above-identified application as listed in the following, and as set forth on the following pages:

Amendments to the Claims; and

Remarks are included following the amendments.